Abstract

Multilayer microstructural device comprising a first and a second layer, which layers are aligned relative to each other by mating alignment structures. The first layer is a positive replication of a microstructural master comprising a number of microstructural elements, the second layer is a negative replication of the same microstructural master, and each pair of mating alignment structures originate from the same microstructural element on the master.

(Fig. 1)

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